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JUL 8 9 2004  
P A T E N T & T R A D E M A R K S U R V E Y  
Docket No.: H6808.0040/P040  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Yoshihiro Kimura et al.

Application No.: 10/779,749

Confirmation No.: 2045

Filed: February 18, 2004

Art Unit: Not Yet Assigned

For: METHOD OF DETERMINING THE  
CONCAVITY AND CONVEXITY ON  
SAMPLE SURFACE, AND CHARGED  
PARTICLE BEAM APPARATUS

Examiner: Not Yet Assigned

**CLAIM FOR PRIORITY AND SUBMISSION OF DOCUMENTS**

U.S. Patent and Trademark Office  
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Dear Sir:

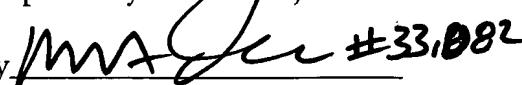
Applicant hereby claims priority under 35 U.S.C. 119 based on the following prior foreign application filed in the following foreign country on the date indicated:

Country	Application No.	Date
Japan	2003-040494	February 19, 2003

In support of this claim, a certified copy of the said original foreign application is filed herewith.

Dated: July 8, 2004

Respectfully submitted,

By  #33,082

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( Translation )

JAPAN PATENT OFFICE

This is to certify that the annexed is a true copy of  
the following application as filed with this Office.

Date of Application: February 19, 2004

Application Number: Japanese Patent Application  
No. 2003-040494

Applicant(s): Hitachi High-Technologies Corporation

April 27, 2004

Commissioner,  
Japan Patent Office                    Yasuo Imai (seal)

Certificate No. 2004-3036312